The invention relates to a micro-scale electromagnetic actuator with linear vibration resistant resonator for high current applications.

Presently, resonators are manufactured using two wafer processes which leads to formation of residual stresses and affects the functionality.

The invention provides a method for manufacturing of microelectromechanical systems (MEMS) ring resonator using single wafer process for high current applications.

Key features of the invention:

- Involves single wafer process
- Uses bulk micro-machining process without stresses
- Low cost raw material
- Structure has features from micro to macro scale
- No requirement of doping
- Process compatibility towards device release after/before dicing process

An application for patent has been filed in India. We are seeking for a commercial partner for licensing and development of this technology.